

Attorney Docket No. 033082 M 275



PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants : Kazuhide HASEBE, et al. Confirmation No.: 6774  
U.S. Serial No. : 10/552,262  
Filed : October 5, 2005  
Examiner : Lan Vinh  
Group Art. Unit : 1792  
For : SILICON DIOXIDE FILM REMOVING METHOD AND  
PROCESSING SYSTEM

**RESPONSE AS "SUBMISSION" UNDER 37 C.F.R. 1.114  
WITH REQUEST FOR CONTINUED EXAMINATION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**MAIL STOP: RCE**

Sir:

In response the Advisory Action mailed on August 11, 2008, for which the time for response is set to expire October 25, 2008, please amend the above-identified application as set forth below and consider the following remarks. Also enclosed is a Petition for a 3 month Extension of Time with requisite fees as well as a Request for Continued Examination with requisite fee.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.